

FORM PTO-1449 (REV. 7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. <b>854063.618D1</b>		APPLICATION NO. <b>101712211</b>	
<b>INFORMATION DISCLOSURE STATEMENT</b> <i>(Use several sheets if necessary)</i>				APPLICANTS <b>Pietro Erratico et al.</b>			
				FILING DATE <b>November 12, 2003</b>		GROUP ART UNIT <b>8815</b>	
<b>U.S. PATENT DOCUMENTS</b>							
*EXAMINER INITIAL	AA	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<b>982</b>		<b>3,969,168</b>	<b>07/13/76</b>	<b>Kuhn</b>	<b>156</b>	<b>17</b>	/
<b>982</b>	<b>AB</b>	<b>4,993,143</b>	<b>02/19/91</b>	<b>Sidner</b>	<b>29</b>	<b>621.1</b>	
<b>982</b>	<b>AC</b>	<b>5,773,870</b>	<b>06/30/98</b>	<b>Su et al.</b>	<b>257</b>	<b>531</b>	
<b>982</b>	<b>AD</b>	<b>6,001,666</b>	<b>12/14/99</b>	<b>Diem et al.</b>	<b>438</b>	<b>52</b>	
<b>982</b>	<b>AE</b>	<b>6,015,761</b>	<b>01/18/00</b>	<b>Merry et al.</b>	<b>438</b>	<b>727</b>	
<b>FOREIGN PATENT DOCUMENTS</b>							
		DOCUMENT NUMBER	DATE	COUNTRY	<i>class/subclass</i>		TRANSLATION YES NO
<b>982</b>	<b>AF</b>	<b>JP62076783</b>	<b>04/08/87</b>	<b>Japan (Abstract Only)</b>			
<b>982</b>	<b>AG</b>	<b>JP62076784</b>	<b>04/08/87</b>	<b>Japan (Abstract Only)</b>			
<b>982</b>	<b>AH</b>	<b>WO9417558</b>	<b>08/04/94</b>	<b>PCT</b>			
<b>982</b>	<b>AI</b>	<b>0 658 927 A</b>	<b>06/21/95</b>	<b>Europe (+ Abstract)</b>			
<b>982</b>	<b>AJ</b>	<b>960177-7 A</b>	<b>11/10/97</b>	<b>Sweden (+ Abstract)</b>			
<b>982</b>	<b>AK</b>	<b>196 21 349 A</b>	<b>12/04/97</b>	<b>Germany (+ Abstract)</b>			
<b>982</b>	<b>AL</b>	<b>1 043 770 A1</b>	<b>10/11/00</b>	<b>EP</b>			
<b>982</b>	<b>AM</b>	<b>1 130 631 A1</b>	<b>09/05/01</b>	<b>EP</b>			
<b>OTHER PRIOR ART</b> <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>							
<b>982</b>	<b>AN</b>	Schubert, "Method of Making Separate Regions of Various Average Depths with One Anisotropic Etch," Research Disclosure, No. 316, Emsworth, GB, August, 1990, pp. 688-689.					
<b>982</b>	<b>AO</b>	Zou et al., "Single-Chip Fabrication of Integrated Fluid System (IFS), <i>IEEE Workshop on Micro Electro Mechanical Systems</i> , New York, NY: IEEE, 25 January 1998, pp 448-453					
<b>982</b>	<b>AP</b>	"Method of Making Separate Regions of Various Average Depths with one Anisotropic Etch," <i>Research Disclosure, GB, Industrial Opportunities Ltd., Havant, No. 316</i> , August 1990					
<b>982</b>	<b>AQ</b>	Sugiyama et al., "Micro-Diaphragm Pressure Sensor," <i>1986 IEEE</i> , 8.3, 184-IEDM, pp 184-187.					
EXAMINER <b>982 E. E. E.</b>				DATE CONSIDERED <b>10/6/04</b>			
* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).							